

High Growth Temperature Studies of InGaAs/InAlAs Superlattices for High-Quality QCL and QWIP Applications

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Motivations:

1. MBE QCL growth temperature is typically below 550 degree C. MOCVD QCL growth temperature is usually above 650 degree C. MOCVD grown bulk crystals can provide lower defects materials
2. The interface defects in MOCVD grown QCLs and superlattice materials can create problems for QCL and superlattice device performance.
3. **The purpose of the research is to**
 - (a) **Explore the high growth temperature limit and**
 - (b) **Investigate how to control interface defects in MOCVD grown QCL and superlattice materials.**

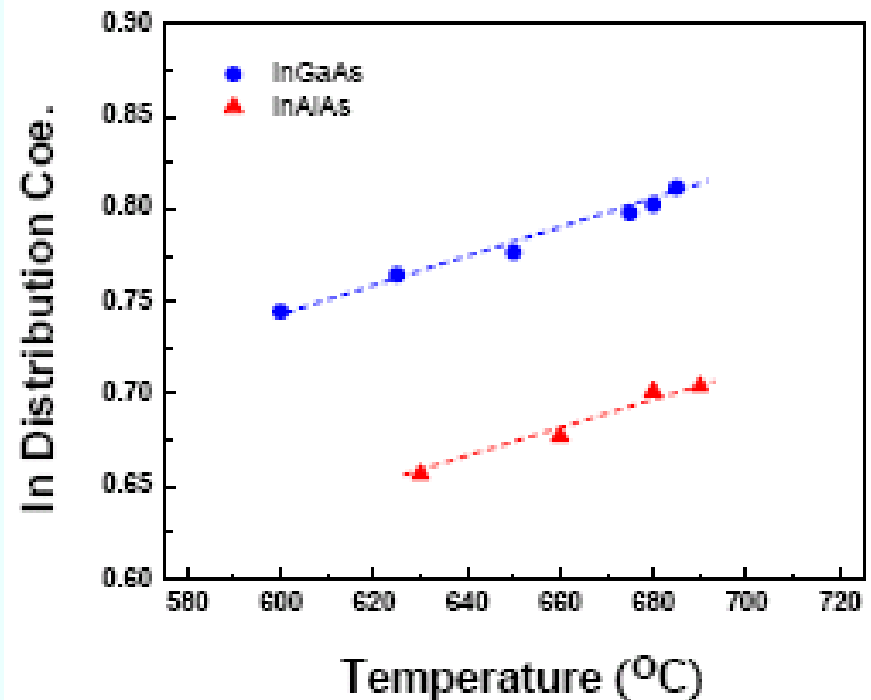
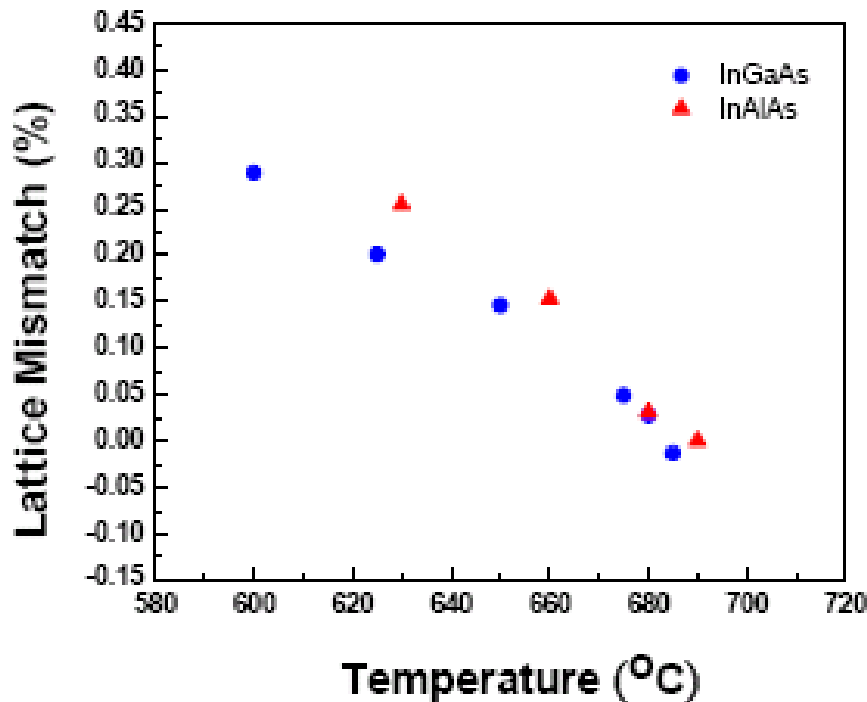
Introduction

1. InGaAs/InAlAs quantum well system is the primary material system in this study. It is good for mid-infrared (3~ 12 μ m) QCLs.
2. The high growth temperature limits of InGaAs and InAlAs films were studied. Material Source are:
In: Trimethylindium (TMI)
Ga: Trimethylgallium (TMG)
Al: Trimethylaluminum (TMA)
As: Arsine (AsH₃)
3. Study on InGaAs/InAlAs superlattices was then conducted to search the optimized growth parameters for superlattice and QCL growths.

Epitaxial Growth of InGaAs and InAlAs

- **Strain vs. Growth Temperature**

When growth temperature increases, the mismatch becomes more compressive (Indium rich). This is caused by higher decomposition rate of TMI at higher temperature.

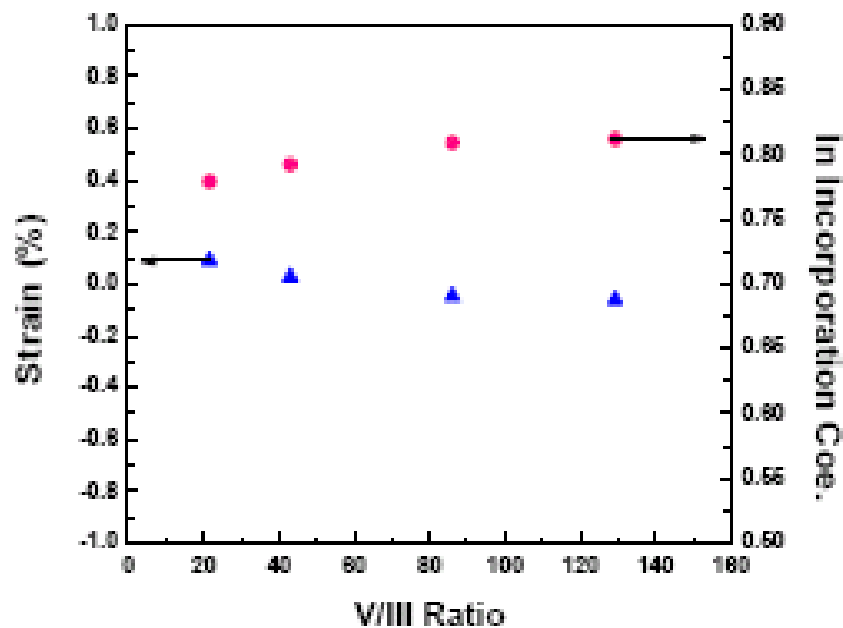


Epitaxial Growth of InGaAs and InAlAs

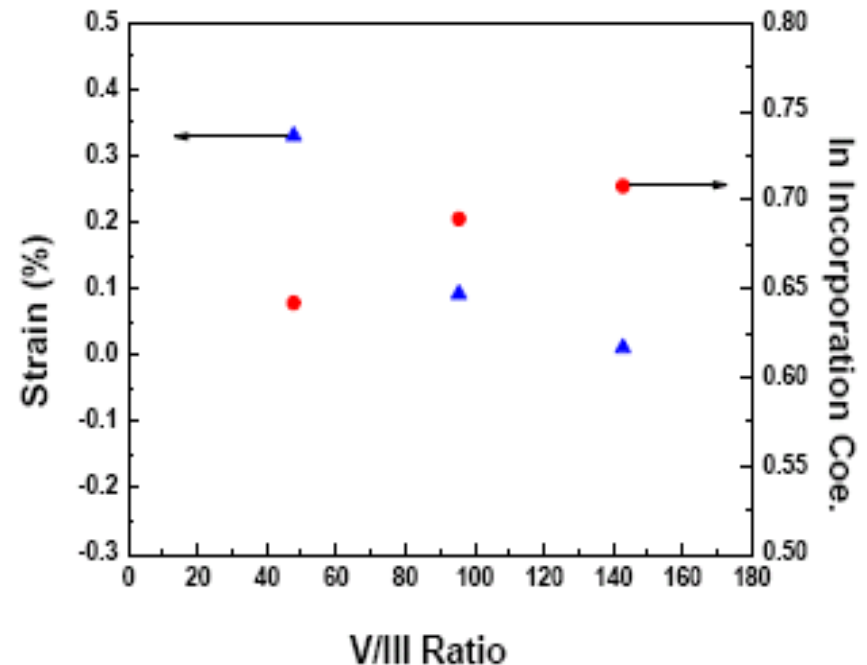
V/III Ratio Effect:

Bonding between Al-As atoms is easier to form than that of the In-As atoms. As a result, In atoms have lower incorporation coefficient. When the V/III ratio decreases, the epitaxial films become more compressive.

InGaAs



InAlAs

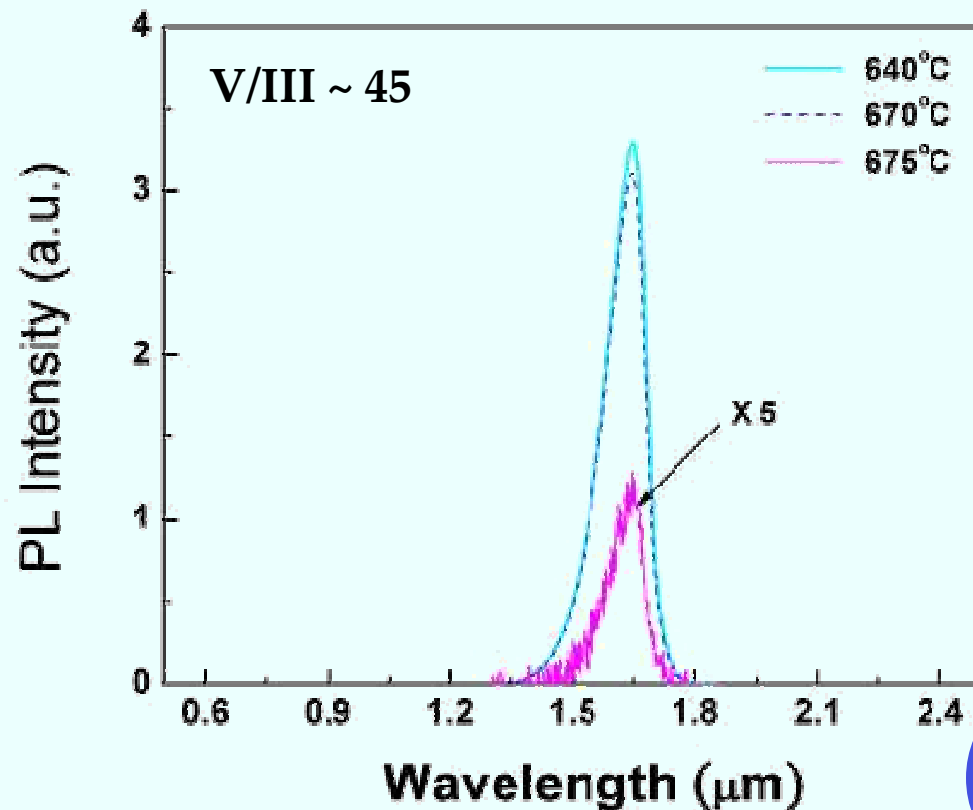


Optimization of InGaAs Epilayers

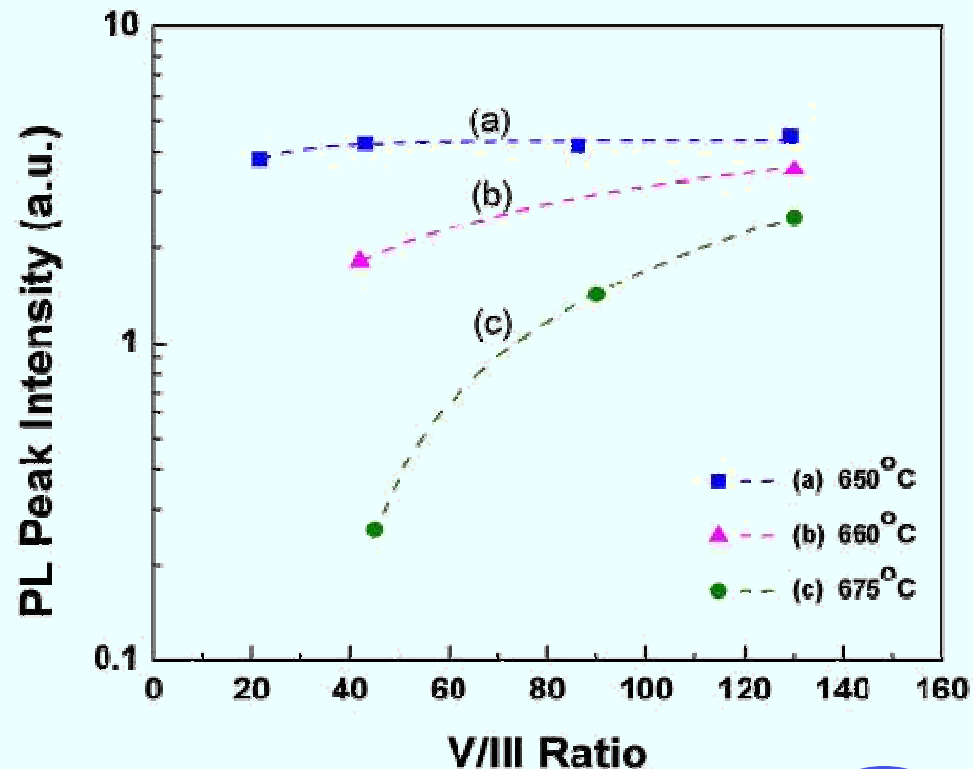
Effects of Growth Temperature



- As the growth temperature increased, more As atoms desorbed from the epilayers.



- Low temperature is good for the growth of InGaAs.
- High temperature growth requires more AsH₃ to compensate the desorption loss of As from the surface.



Optimization of InAlAs Epilayers

■ V/III Ratio Effects:

Worse surface morphology produced at higher AsH_3

V/III ~ 60

V/III ~ 150

■ Buffer Layer Effects:

InGaAs buffer layer can improve the InAlAs because of smooth growth front and less impurities.

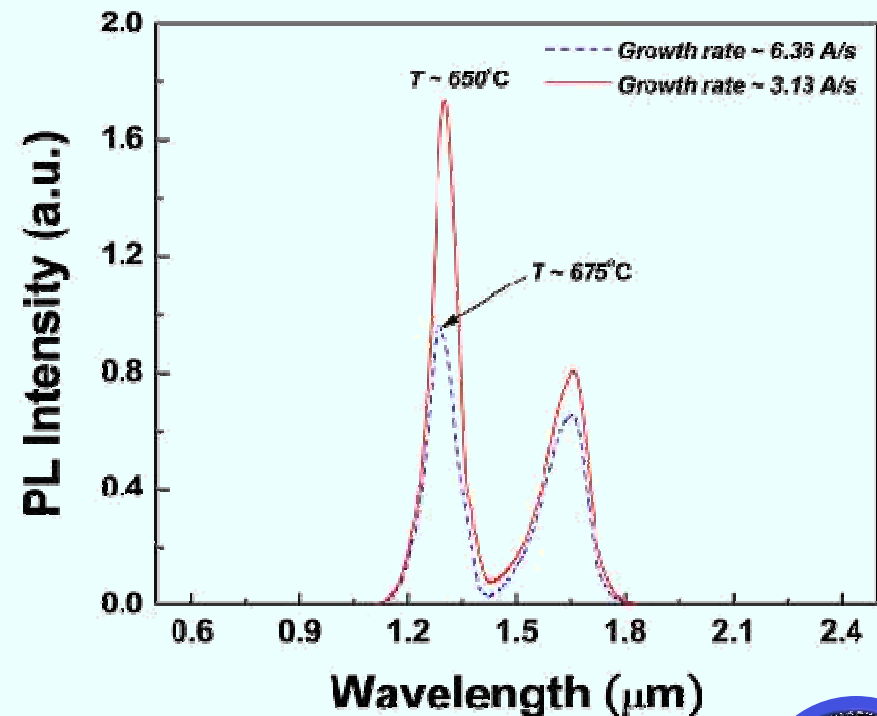
Grown on InGaAs buffer layer

Grown on InP substrate

InGaAs/InAlAs Superlattices

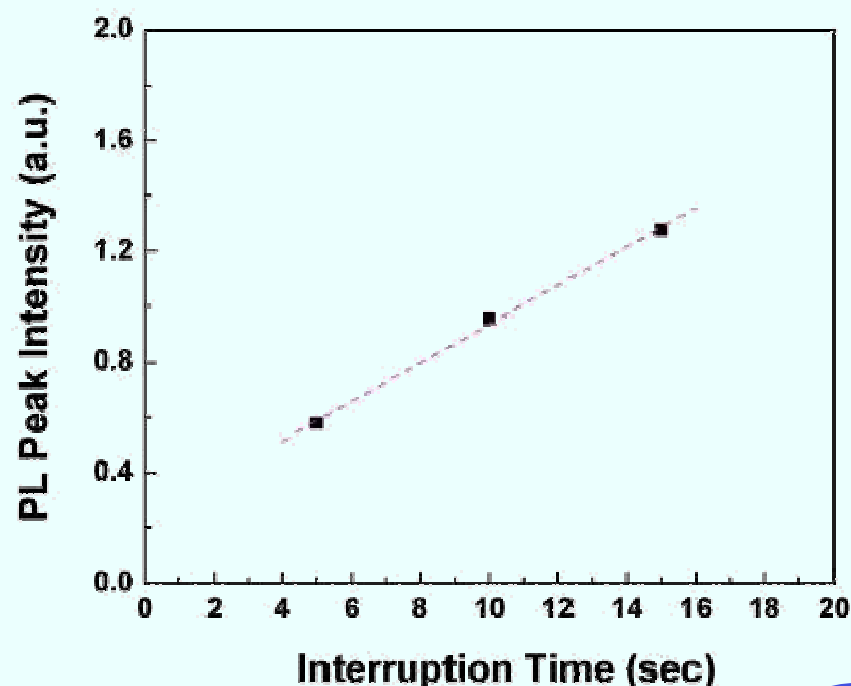
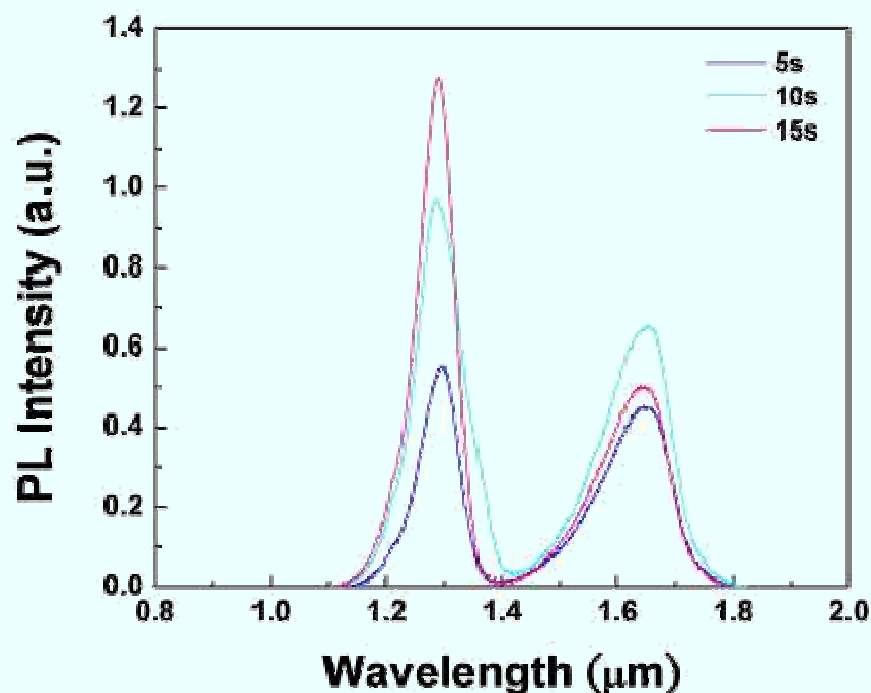
Despite high growth temperature utilized to reduce the impurities, PL intensity is worse at higher growth rate which is necessarily used to avoid surface decomposition.

Total ~ 30 periods	InP cap layer	10 nm
	⋮	
Unit structure	In _{0.52} Al _{0.48} As barrier	10 nm
	In _{0.53} Ga _{0.47} As well	3.2 nm
	In _{0.52} Al _{0.48} As barrier	2.0 nm
	In _{0.53} Ga _{0.47} As well	2.2 nm
	In _{0.52} Al _{0.48} As barrier	50 nm
	In _{0.53} Ga _{0.47} As buffer layer	50 nm
	InP substrate	



- To improve the interface quality at high growth temperatures and growth rates, effects of interruption periods between individual layers were investigated.

- Longer interruption by AsH₃ purging enhances the PL intensity.



Summary

- To grow high-quality InGaAs films, high growth temperature is preferred to reduce impurities. However, the surface will decompose at higher temperature. To remedy this, high V/III ratio needs to be used for compensating the surface decomposition.
- To grow high-quality InAlAs films, the growth temperature has to be as high as possible. V/III ratio cannot be too low because the group V atoms will decompose; however, it cannot be too high since the Al atoms will be prohibited to migrate to their desired sites, which will affect the surface morphology.
- To grow high-quality InGaAs/InAlAs superlattice, high growth temperature is required ($\sim 660^{\circ}\text{C}$) and V/III ratio needs to be controlled during 50 ~ 150. By interrupting the growth process between individual layers with longer purging time, high-quality superlattices were obtained.